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Part 50: MEMS capacitive microphones

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Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this International Standard is English.

This document was drafted in accordance with ISO/IEC Directives, Part 2, and developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC Supplement, available at www.iec.ch/members_experts/refdocs. The main document types developed by IEC are described in greater detail at www.iec.ch/publications.

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- reconfirmed,
- withdrawn, or
- revised.

SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

Part 50: MEMS capacitive microphones

1 Scope

This part of IEC 62047 defines the test conditions and test methods for the performance of MEMS capacitive microphones.

This document applies to MEMS capacitive microphones.

2 Normative references

The following documents are referred to in the text in such a way that some or all of their content constitutes requirements of this document. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

IEC 61193-2, *Quality assessment systems – Part 2: Selection and use of sampling plans for inspection of electronic components and packages*